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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/922,804	08/07/2001	Michikazu Matsumoto	740819-610	8887
22204	7590 06/10/2004		EXAM	INER
NIXON PEABODY, LLP 401 9TH STREET, NW			ERDEM, FAZLI	
SUITE 900	· · · · · · · · · · · · · · · · · · ·		ART UNIT	PAPER NUMBER
WASINGTON, DC 20004-2128			2826	
		DATE MAILED: 06/10/2004		

Please find below and/or attached an Office communication concerning this application or proceeding.

		an			
	Application No.	Applicant(s)			
	09/922,804	MATSUMOTO ET AL.			
Office Action Summary	Examiner	Art Unit			
`	Fazli Erdem	2826			
The MAILING DATE of this communication app Period for Reply	ears on the cov r sheet with the	correspondenc address			
A SHORTENED STATUTORY PERIOD FOR REPL' THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.1: after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period v  - Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be to within the statutory minimum of thirty (30) do will apply and will expire SIX (6) MONTHS fro, cause the application to become ABANDON.	imely filed  ays will be considered timely.  m the mailing date of this communication.  IED (35 U.S.C. § 133).			
Status					
Responsive to communication(s) filed on 19 May 2004.  This action is FINAL.  2b) This action is non-final.  Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims					
4)  Claim(s) 4-6 and 8-10 is/are pending in the appearance of the above claim(s) is/are withdraw 5)  Claim(s) 4,5,8 and 9 is/are allowed.  6)  Claim(s) 6 and 10 is/are rejected.  7)  Claim(s) is/are objected to.  8)  Claim(s) are subject to restriction and/o	wn from consideration.				
Application Papers		•			
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) accomplicated any accomplicated any not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Examine	epted or b) objected to by the drawing(s) be held in abeyance. S ion is required if the drawing(s) is o	ee 37 CFR 1.85(a). bjected to. See 37 CFR 1.121(d).			
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Applica rity documents have been receiv u (PCT Rule 17.2(a)).	tion No ved in this National Stage			
Attachment(s)  1) Notice of References Cited (RTO 802)	A) []  -t	ov (PTO 442)			
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date</li> </ol>	4) Interview Summar Paper No(s)/Mail I 5) Notice of Informal 6) Other:				

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#### **DETAILED ACTION**

## Allowable Subject Matter

1. Claims 4, 5, 8 and 9 allowed.

### Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

- (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claim 6 rejected under 35 U.S.C. 103(a) as being unpatentable over Chang et al. (6,346,467) in view of Hsu et al. (5,759,916).

Regarding Claim 6, Chang et al. disclose a method of making tungsten gate MOS transistor and memory cell by encapsulating where in Fig 1(a), polysilicon layer 3 is deposited or gate oxide layer 2. On top of polysilicon layer 3, a barrier layer or titanium nitride 3 has been deposited. A tungsten gate electrode layer 5 is deposited on barrier layer 3. Column 6 describes that the annealing has been done over temperatures 800 Celcius. Chang et al. fail to disclose the required stoichometric ratio of titanium being rich compared to nitride in the barrier layer. However, Hsu et al. disclose a method for forming a void-free titanium nitride anti-reflective coating layer upon an aluminum containing conductor layer where in the abstract section the required stoichiometric ratio is disclosed.

It would have been obvious to one of having ordinary skill in the art at the time the invention was made to include the required stoichiometric ratio of titanium to nitride in Chang et al. as taught by Hsu et al. in order to have an electrode structure with higher reliability.

3. Claim 10 rejected under 35 U.S.C. 103(a) as being unpatentable over Chang et al. (6,346,467) in view of Hsu et al. (5,759,916) further in view of Konecni et al. (6,215,186).

Regarding Claim 10, Chang et al. disclose a method of making tungsten gate MOS transistor and memory cell by encapsulating where in Fig 1(a), polysilicon layer 3 is deposited or gate oxide layer 2. On top of polysilicon layer 3, a barrier layer or titanium nitride 3 has been deposited. A tungsten gate electrode layer 5 is deposited on barrier layer 3. Column 6 describes that the annealing has been done over temperatures 800 Celcius. Chang et al. fail to disclose the required stoichometric ratio of titanium being rich compared to nitride in the barrier layer and the second barrier layer or titanium nitride. However, Hsu et al. disclose a method for forming a void-free titanium nitride anti-reflective coating layer upon an aluminum containing conductor layer where in the abstract section the required stoichiometric ratio is disclosed. Furthermore, Konecni et al. disclose a system of method of forming a tungsten plug where in Fig 5, 18 is the first titanium nitride layer and 20 is the second titanium nitride layer.

It would have been obvious to one of having ordinary skill in the art at the time the invention was made to include the required stoichiometric ratio of titanium to nitride and the second barrier layer of titanium nitride in Chang et al. as taught by Hsu et al. and Konecni et al. in order to have an electrode structure with higher reliability.

#### Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Fazli Erdem whose telephone number is (571) 272-1914. The examiner can normally be reached on M - F 8:00 - 5:00.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan Flynn can be reached on (571) 272-1915. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

FE June 2, 2004

NATHAN J. FLYNN SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2800